

IUCrJ

Volume 8 (2021)

Supporting information for article:

Synchrotron total-scattering data applicable to dual-space structural analysis

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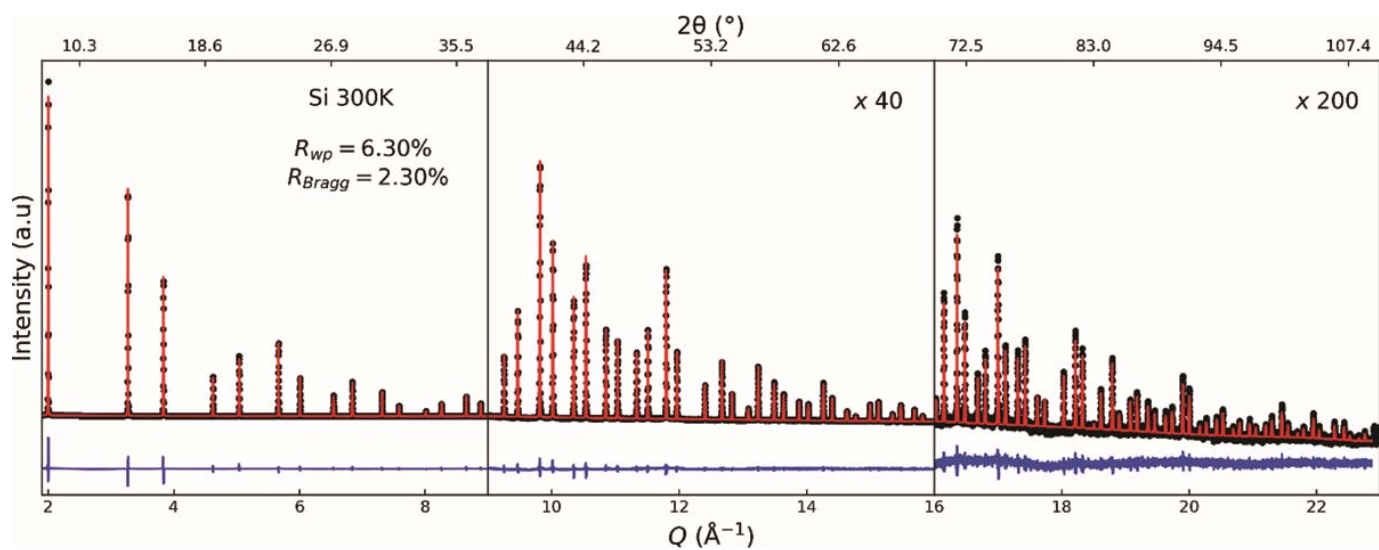


Figure S1 Rietveld analysis results of the total scattering data of Si at 300 K obtained through OHGI. Black dots, red lines, and blue lines show data points, calculated model, and their differences, respectively.

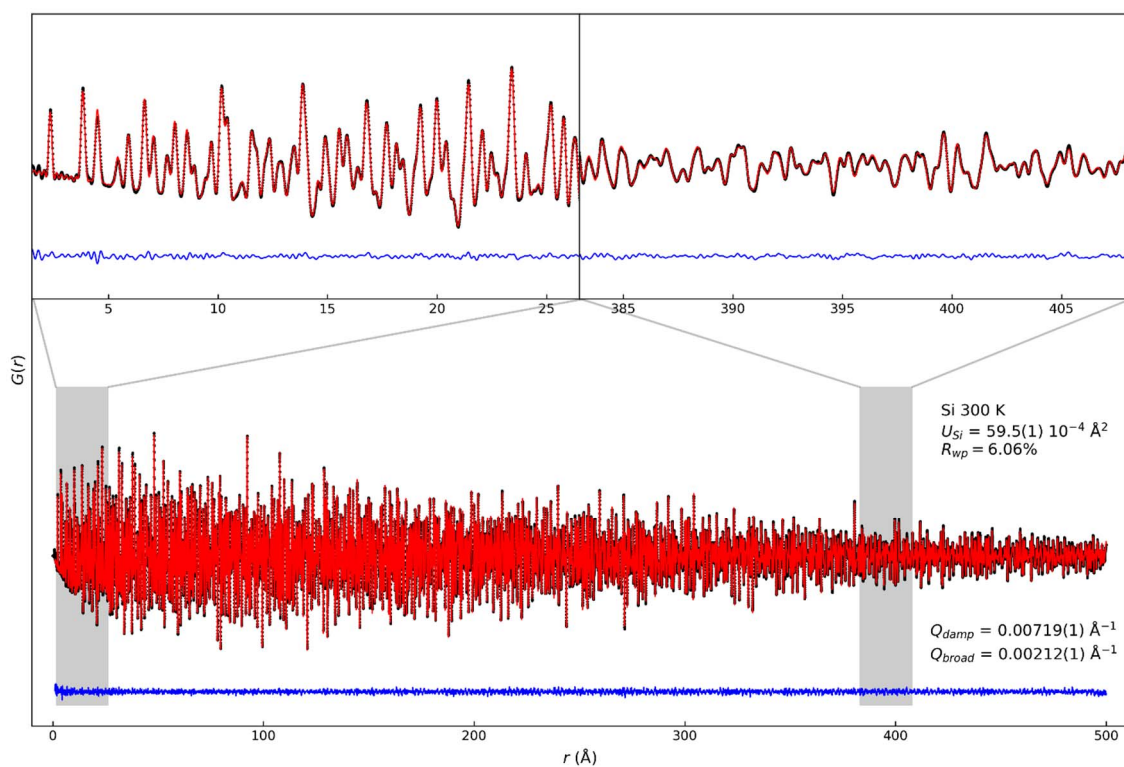


Figure S2 PDF analysis results of the Si data at 300 K in a range up to $r = 500 \text{ \AA}$. Black dots, red lines, and blue lines show data points, calculated model, and their differences, respectively.

Table S1 Experimental details for LaB₆ data

Facility	Beamline and detector	Sample-to-detector distance (mm)	Experiment Date	Energy (keV)	Capillary material and diameter (mm)	Beam size (horizontal x vertical) (mm ²)
PETRA III	P21.1 PE	300	Sep. '19	100	Kapton 1.0	0.8 x 0.8
	P21.1 PE	415	Nov. '19	100	Kapton 1.0	1.2 x 1.2
	P21.1 PE	850	Nov. '19	100	Kapton 1.0	1.2 x 1.2
	P02.1 PE	220	Dec. '18	60	Kapton 1.0	1 x 1
	P02.1 PE	470	Dec. '18	60	Kapton 1.0	1 x 1
	P02.1 PE	999	Nov '16	60	Kapton 1.0	1 x 1
	P02.1 AVID	1200	April '18	60	Glass 0.2	0.3 x 0.3
SPring-8	BL44B2 Image-plate	286.48	Dec. '16	24.80	Glass 0.1	3.0 x 0.5
	BL44B2 OHGI	286.48	Oct. '18	27.46(6)	Glass 0.1	3.0 x 0.5

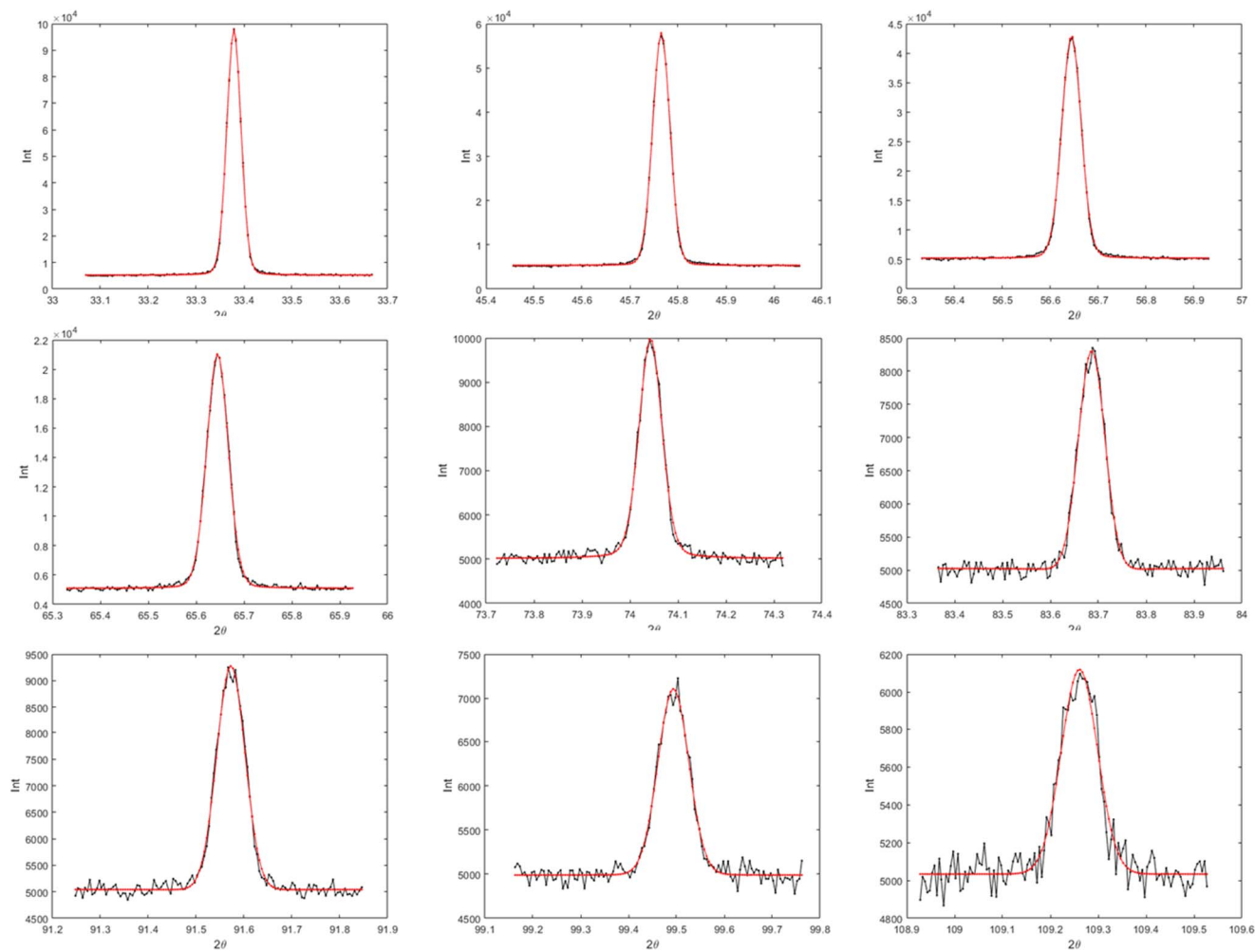


Figure S3 Single peak fits of diffraction peaks from Si 100K.